IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Art Unit: 2815 Examiner: Mr. William F. Kraig

In re PATENT APPLICATION of:

Applicant	:	Akira TAKAHASHI)	
Serial No.	:	10/798,482	
Filed	:	March 12, 2004	<u>AMENDMENT</u>
For	:	DRY ETCHING METHOD FOR SEMICONDUCTOR DEVICE	
Attorney Ref.	:	OKI 414	April 27, 2006

Mail Stop AF
Director of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is responsive to the Office Action of November 1, 2005, the period for reply to which is being extended to expire on May 1, 2006 by a Petition filed concurrently herewith. Furthermore, a Request for Continued Examination (RCE) is being filed concurrently.

Please amend the above-identified application as specified on the following pages, and then reconsider the application in view of the Remarks that are presented thereafter.

FEE ENCLOSED:\$ ////
Please charge any further
fee to our Deposit Account
No. 18-0002